TFD Materials and Components Japan TC Chapter and FPD Metrology Japan TC Chapter Joint Meeting
Meeting Summary and Minutes

SEMI Japan Standards Spring 2017 Meetings
Friday, April 7, 2017, 15:00-17:00
SEMI Japan, Tokyo, Japan

TC Chapter Announcements

FPD Materials & Components Japan TC Chapter:
SEMI Japan Standards Fall 2017 Meetings
Friday, September 15, 2017, 15:00-17:00
SEMI Japan, Tokyo, Japan

FPD Metrology Japan TC Chapter:
SEMI Japan Standards Fall 2017 Meetings
Friday, September 15, 2017, 15:00-17:00
SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

<table>
<thead>
<tr>
<th>Company</th>
<th>Last</th>
<th>First</th>
<th>Company</th>
<th>Last</th>
<th>First</th>
</tr>
</thead>
<tbody>
<tr>
<td>ITRI</td>
<td>Bao-Jen</td>
<td>Pong</td>
<td>Andy</td>
<td></td>
<td></td>
</tr>
<tr>
<td>Sumitomo Bakelite</td>
<td>Eguchi</td>
<td>Toshimasa</td>
<td>Nitto Denko</td>
<td>Tatsumi</td>
<td>Motoshige</td>
</tr>
<tr>
<td>Yamagata University</td>
<td>Furukawa</td>
<td>Tadahiro</td>
<td>Sony</td>
<td>Tomioka</td>
<td>Satoshi</td>
</tr>
<tr>
<td>Fujifilm</td>
<td>Shibahara</td>
<td>Yoshi</td>
<td>Japan Display</td>
<td>Watanabe</td>
<td>Ryoichi</td>
</tr>
<tr>
<td>Teijin</td>
<td>Ito</td>
<td>Haruhiko</td>
<td>SEMI Japan</td>
<td>Tejima</td>
<td>Naoko</td>
</tr>
<tr>
<td>Otsuka Electronics</td>
<td>Kawaguchi</td>
<td>Akira</td>
<td></td>
<td></td>
<td></td>
</tr>
</tbody>
</table>

* alphabetical order by last name

Table 2 Leadership Changes

<table>
<thead>
<tr>
<th>Group</th>
<th>Previous Leader</th>
<th>New Leader</th>
</tr>
</thead>
<tbody>
<tr>
<td>Polarizing Film Task Force Co-leaders</td>
<td>Toshihito Otsuka (Sanritz) - Yoshi Shibahara (Fujifilm) - Motoshige Tatsumi (Nitto Denko)</td>
<td>Yoshi Shibahara (Fujifilm) - Motoshige Tatsumi (Nitto Denko)</td>
</tr>
</tbody>
</table>

Table 3 Ballot Results

Passed ballots and line items will be forwarded to the ISC Audit & Review Subcommittee for procedural review.
Failed ballots and line items were returned to the originating task forces for re-work and re-balloting.

FPD M&C Japan TC Chapter

<table>
<thead>
<tr>
<th>Document #</th>
<th>Document Title</th>
<th>Committee Action</th>
</tr>
</thead>
<tbody>
<tr>
<td>6103</td>
<td>Line Item Revision to SEMI D63-0811, Measurement Method for Depolarization Effect of FPD Color Filter with Title Change to. Test Method for Depolarization Effect of. FPD Color Filter</td>
<td>Failed</td>
</tr>
</tbody>
</table>

FPD M&C Japan TC Chapter

and FPD Metrology Japan TC Chapter

Meeting Minutes
**FPD Metrology Japan TC Chapter**

<table>
<thead>
<tr>
<th>Document #</th>
<th>Document Title</th>
<th>Committee Action</th>
</tr>
</thead>
<tbody>
<tr>
<td>6101</td>
<td>Line Item Revision to SEMI D31-0213, with title change from “Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection” to “Guide for Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection”</td>
<td>Passed as balloted</td>
</tr>
</tbody>
</table>

**Table 4 Authorized Activities**

**FPD M&C Japan TC Chapter**

None.

**FPD Metrology Japan TC Chapter**

None.

**NOTE 1:** SNARFs and TFOFs are available for review on the SEMI Web site at: [http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF](http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF)

**Table 5 Authorized Ballots**

**FPD M&C Japan TC Chapter**

<table>
<thead>
<tr>
<th>Doc.#</th>
<th>When</th>
<th>SC/TF/WG</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>5977</td>
<td>Cycle 5, 2017</td>
<td>Flexible Display TF</td>
<td>New Standard, Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices</td>
</tr>
</tbody>
</table>

**Table 6 New Action Items**

**FPD M&C Japan TC Chapter**

<table>
<thead>
<tr>
<th>Item #</th>
<th>Assigned to</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>FPD M&amp;C 170407-01</td>
<td>FPD Color Filter TF</td>
<td>To rework for the Document 6103 (Line Item Revision to SEMI D63-0811)</td>
</tr>
<tr>
<td>FPD M&amp;C 170407-02</td>
<td>SEMI Staff</td>
<td>To request GCS review of revision SNARF of Doc. 6104, SEMI D60-0710: Test Method of Surface Scratch Resistance for FPD Polarizing Film and Its Materials, with title change to: Test Method of Surface Scratch Resistance for FPD Polarizing Film and Cover Plastics for Mobile Display, after 2-weeks review by TC members.</td>
</tr>
<tr>
<td>FPD M&amp;C 170407-03</td>
<td>SEMI Staff</td>
<td>To submit Doc. 5977, New Standard, Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices, for Cycle 5, 2017</td>
</tr>
</tbody>
</table>

**FPD Metrology Japan TC Chapter**

<table>
<thead>
<tr>
<th>Item #</th>
<th>Assigned to</th>
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</tr>
</thead>
<tbody>
<tr>
<td>FPD Met 170407-01</td>
<td>SEMI Staff</td>
<td>To forward adjudication result of Doc. 6101, Line Item Revision of SEMI D31-0914, Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection, with title change to: Guide for Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection, to the ISC A&amp;R Subcommittee for procedural review</td>
</tr>
</tbody>
</table>
### Table 7 Previous Meeting Action Items

**FPD M&C Japan TC Chapter**

<table>
<thead>
<tr>
<th>Item #</th>
<th>Assigned to</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>FPD M&amp;C 160701-05</td>
<td>SEMI Staff</td>
<td>To contact Mr. Otsuka and ask him his intention, and request him to send his replacement, if he will decline the co-leader position. <strong>Closed</strong></td>
</tr>
<tr>
<td>FPD M&amp;C 161109-01</td>
<td>SEMI Staff</td>
<td>To submit Line Item Revision to SEMI D63-0811, Measurement Method for Depolarization Effect of FPD Color Filter with Title Change to: Test Method for Depolarization Effect of FPD Color Filter for Cycle 9, 2016. <strong>Closed</strong></td>
</tr>
<tr>
<td>FPD M&amp;C 161109-02</td>
<td>SEMI Staff</td>
<td>To check if the SNARF should be resubmitted, when Scope will be widen and Title will be changed (Doc.#6014). <strong>Closed</strong></td>
</tr>
</tbody>
</table>

**FPD Metrology Japan TC Chapter**

<table>
<thead>
<tr>
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<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>FPD Met 161109-01</td>
<td>SEMI Staff</td>
<td>To submit Line Item Revision of SEMI D31-0914, Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection, with title change to: Guide for Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection. for Cycle 9, 2016. <strong>CLOSE</strong></td>
</tr>
</tbody>
</table>
1 Welcome, Reminders, and Introductions
Tadahiro Furukawa, committee co-chair, called the meeting to order at 15:00. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

2 SEMI Staff Report
Attachment: 01_SEMI_Staff_Report_170407

3 Liaison Reports
3.1 FPD Metrology Korea TC Chapter
Naoko Tejima reported for the FPD Metrology Korea TC Chapter. This report included Leadership, Organization Chart, Meeting Information, Major Updates, Subcommittee/TF/WG Updates and Contact Information
Attachment: 02_Korea_FPD_Liaison_Report_170407

3.2 FPD Metrology Taiwan TC Chapter
Naoko Tejima reported for the FPD Metrology Taiwan TC Chapter. This report included Leadership, Organization Chart, Meeting Information, Ballot Result, FPD Metrology Committee Highlights and Contact Information
Attachment: 03_Taiwan_Liaison_Report_170407

[FPD Materials & Components Japan TC Chapter Part]

4 Review of Previous Meeting Minutes
The TC Chapter reviewed the minutes of the previous meeting.
It was pointed followings:
- “To submit ballot of Line Item Revision to SEMI D63-0811, …Motion passed.” should be deleted.

Motion: To approve the minutes of the previous meeting as written after the above a point is corrected.
By / 2nd: Yoshi Shibahara (Fujifilm) / Motoshige Tatsumi (Nitto Denko)
Discussion: None
Vote: 8 in favor and 0 opposed. Motion passed.
Attachment: 04_JA_FPD_M+C_Previous_Mtg_Minutes_170407

5 Ballot Review
5.1 Doc.6103, Line Item Revision to SEMI D63-0811, Measurement Method for Depolarization Effect of FPD Color Filter with Title Change to: Test Method for Depolarization Effect of FPD Color Filter
This document failed committee review.
Action Item: FPD Color Filter Task Force to rework for the Document 6103
Attachment: 05_6103_Ballot_Report_170407

6 Task Force Reports
6.1 Polarizing Film Task Force
Yoshi Shibahara reported as follows:
- Regarding Doc. 6014 Revision to SEMI D60-0710: Test Method of Surface Scratch Resistance for FPD Polarizing Film and Its Materials, the Scope will be widen and Title will be changed. Revision SNARF will be reviewed and will get the approval by the GCS.

Action Item: SEMI to request GCS review of revision SNARF of Doc.6014, SEMI D60-0710: Test Method of Surface Scratch Resistance for FPD Polarizing Film and Its Materials, with title change to: Test Method of Surface Scratch Resistance for FPD Polarizing Film and Cover Plastics for Mobile Display, after 2-weeks review by TC members.
Attachment: 06_Revised_SNARF_for_revision_of_D60_170407
Motoshige Tatsumi reported as follows:


### 6.2 Flexible Display Task Force

Tadahiro Furukawa reported for the Flexible Display Task Force.

- Drafting Doc. 5977, New Standard, Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices.

**Motion:** To submit Doc. 5977, New Standard, Test Method of Water Vapor Barrier Property for Plastic Films with High Barrier for Electronic Devices for Cycle 5, 2017.

**By / 2nd:** Toshimasa Eguchi (Sumitomo Bakelite) / Haruhiko Ito (Teijin)

**Discussion:** None.

**Vote:** 6 in favor and 0 opposed. **Motion passed.**

### 6.3 FPD Color Filter Task Force

Tadahiro Furukawa reported for the FPD Color Filter Task Force. Of note:

- Doc. 6103, Line Item Revision to SEMI D63-0811, Measurement Method for Depolarization Effect of FPD Color Filter with Title Change to: Test Method for Depolarization Effect of FPD Color Filter, failed committee review as previously discussed. (See 5).

### 6.4 FPD Mask Task Force

No Report was provided.

### Old Business

#### 7.1 Previous Meeting Action Items

Naoko Tejima reviewed the old action items. These can be found in the Old Action Items table at the beginning of these minutes.

### New Business

None.
9 Review of Previous Meeting Minutes
The TC Chapter reviewed the minutes of the previous meeting.

Motion: To approve the minutes of the previous meeting as written.
By / 2nd: Tadahiro Fufukawa (Yamagata University) / Akira Kawaguchi (Otsuka Electronics)
Discussion: None
Vote: 6 in favor and 0 opposed. Motion passed.
Attachment: 04_JA_FPD_M+C_Previous_Mtg_Minutes_170407

10 Ballot Review
10.1 Doc.6101, Line Item Revision of SEMI D31-0914, Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection, with title change to: Guide for Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection
This document passed committee review and will be forwarded to the ISC A&R SC for procedural review.
Action Item: SEMI staff to forward adjudication result of Doc.6101 to the ISC A&R Subcommittee for procedural review.
Attachment: 07_6101_Ballot_Report_170407

11 Task Force Reports
11.1 D31 Revision Task Force
Ryoichi Watanabe, Co-leaders of FPD Metrology Japan TC Chapter reported for the D31 Revision Task Force. Of note:
- Doc.6101, Line Item Revision of SEMI D31-0914, Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection, with title change to: Guide for Definition of Measurement Index (DSEMU) for Luminance Mura in FPD Image Quality Inspection; passed committee review as previously discussed. (See 5).

12 Old Business
12.1 Previous Meeting Action Items
Naoko Tejima reviewed the old action items. These can be found in the Old Action Items table at the beginning of these minutes.

13 New Business
None.

14 Action Item Review
14.1 New Action Items
Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

15 Next Meeting and Adjournment
The next meeting of the FPD Materials and Components Japan TC Chapter is scheduled for Friday, September 15, 2017, 15:00-17:00, SEMI Japan, Tokyo, Japan.
The next meeting of the FPD Metrology Japan TC Chapter is scheduled for Friday, September 15, 2017, 15:00-17:00, SEMI Japan, Tokyo, Japan.
See http://www.semi.org/en/events for the current list of meeting schedules.
Having no further business, a motion was made to adjourn. Adjournment was at 17:00.
Table 8 Index of Available Attachments

<table>
<thead>
<tr>
<th>#</th>
<th>Title</th>
</tr>
</thead>
<tbody>
<tr>
<td>1</td>
<td>SEMI_Staff_Report_170407</td>
</tr>
<tr>
<td>2</td>
<td>Korea_FPD_Liaison_Report_170407</td>
</tr>
<tr>
<td>3</td>
<td>Taiwan_Liaison_Report_170407</td>
</tr>
<tr>
<td>4</td>
<td>JA_FPD_M+C_Met_Previous_Mtg_Minutes_170407</td>
</tr>
<tr>
<td>5</td>
<td>6103_Ballot_Report_170407</td>
</tr>
<tr>
<td>6</td>
<td>Revised_SNARF_for_revision_of_D60_170407</td>
</tr>
<tr>
<td>7</td>
<td>6101_Ballot_Report_170407</td>
</tr>
</tbody>
</table>

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.